# AC-LGAD novel geometries exploration by etching of metal on the surface AC-coupled pads

38° RD50 Workshop Dr. Simone M. Mazza (SCIPP, UC Santa Cruz), on behalf of the SCIPP UCSC group

S. M. Mazza, C. Gee, R. Padilla, Y. Zhao, F. McKinney-Martinez, H. F.-W. Sadrozinski, A. Seiden, B. Schumm, R. Arcidiacono, N. Cartiglia, M. Ferrero, M. Mandurrino, V. Sola, M. Boscardin, G. Borghi, G. Paternoster, F. Ficorella, M. Centis Vignali, G.F. Dalla Betta, L. Pancheri, A. Tricoli, G. Giacomini, G. d'Amen, W. Chen, S. Robinson







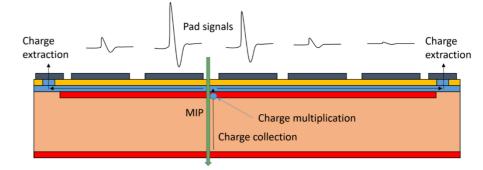
**FONDAZIONE** BRUNO KESSLER



### FBK RSD1 etching and testing

#### FBK AC-LGADs

- AC-LGADs (or RSD) can provide spatial resolution of  ${<}10~\mu m$  with sparse readout
  - Using information from charge sharing between AC-pads
- Sensors produced by FBK (Italy) with square pad of several pitch and pad size: FBK RSD1 production
- Alternative pad configuration the metal layer of the pads was etched to create new geometries such as circles, crosses and micro-strips
  - Pad metal surface was defined at BNL (US) with laserwriter lithography
- The alternative geometries have been studied using a focused IR-Laser scans directed both at the read-out side on the front and the bias side on the back of the sensor



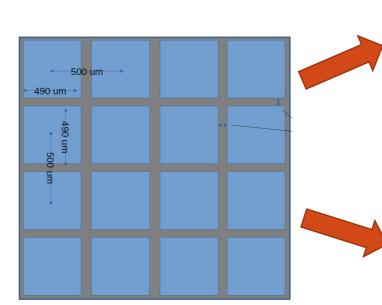


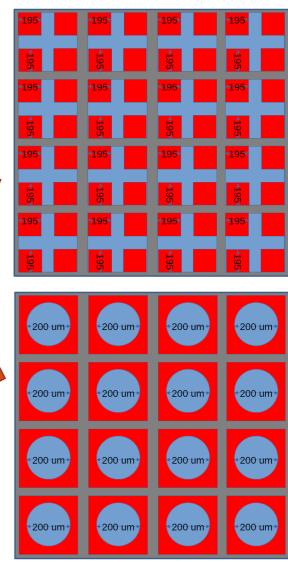
### FBK RSD1 etching for novel geometries

- Etch front metal to produce new AC-LGAD geometries
  - Starting point FBK RSD1 500-490 µm 4x4 pads
  - Sensor also etched on the back to allow back laser illumination

#### Crosses

- Reduce pad capacitance
- Maximize non-metalize area for event reconstruction
- Expect full signal containment within a "box" for reconstruction
- Separation in "boxes" were reconstruction is made with 4 channels
- Circles
  - Easier to model with analytic formula

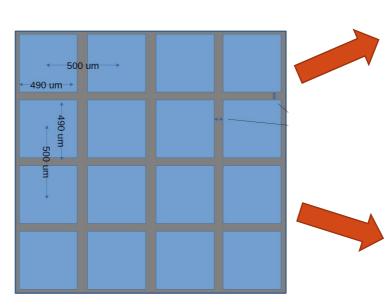


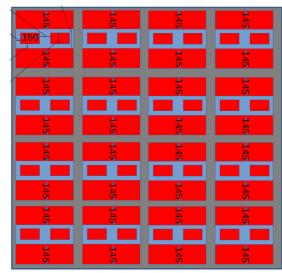


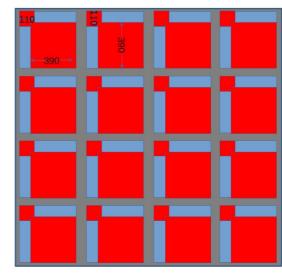
#### FBK RSD1 etching for novel geometries

#### Open microstrips

- Reduce pad capacitance
- Provide bonding pad in the center
- Expect better position resolution across the strips than along the strips
- Microstrip forming boxes
  - Separation in "boxes" were reconstruction is contained with 4 channels
  - Signal containment in the box
  - Reconstruction with simple ratio X/Y (on ASIC level?)
- Small pads with large distance
  - 400um pitch, 100um pad size

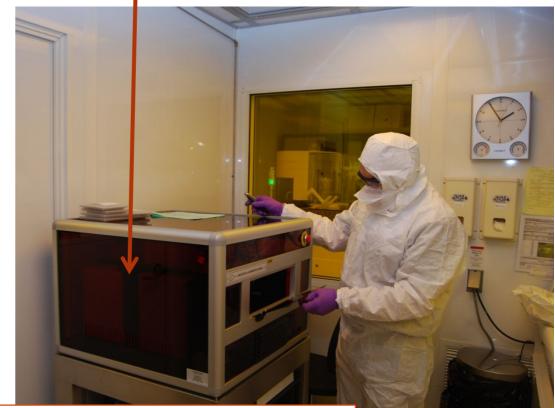






### FBK RSD1 etching procedure (BNL)

- Chip is mounted on a 2" wafer, and held in place with resist.
- After resist spinning, the pattern is transferred to the chip by laser-writer lithography
- After development, a first etching is by RIE to remove the passivation over the aluminum pads
- The aluminum is now exposed and can be etched away with standard aluminum etch (or HF)
- A dip in resist stripper and acetone cleans the chip and separates it from the 2" wafer support

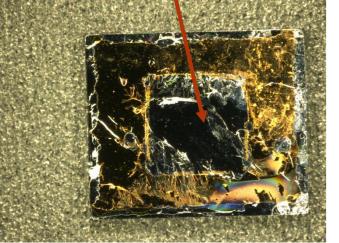


**Very time-consuming procedure !!!!!** 

#### FBK RSD1 etched

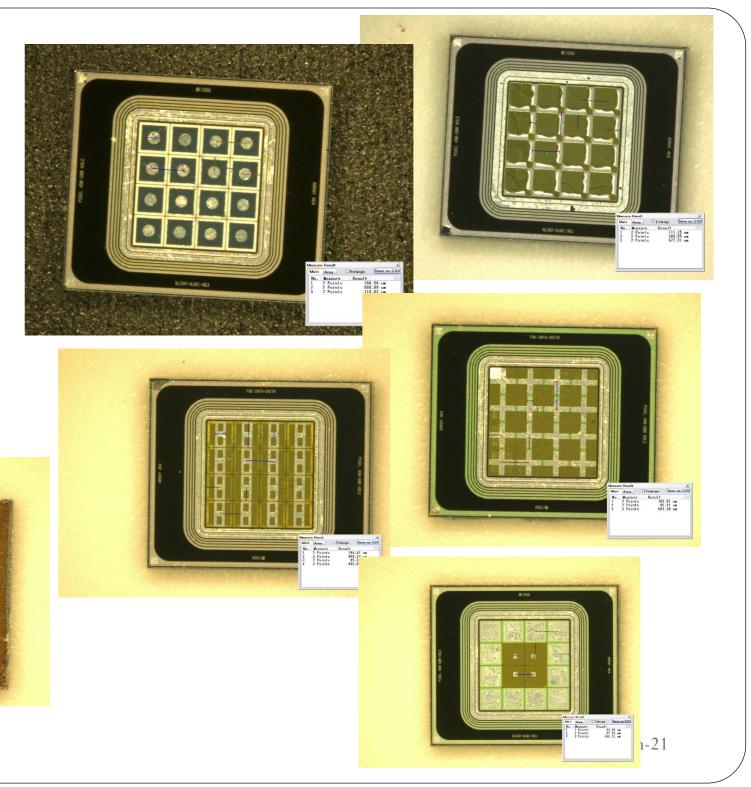
- Procedure quite successful in creating new metal patterns
- Back etching needs some tuning

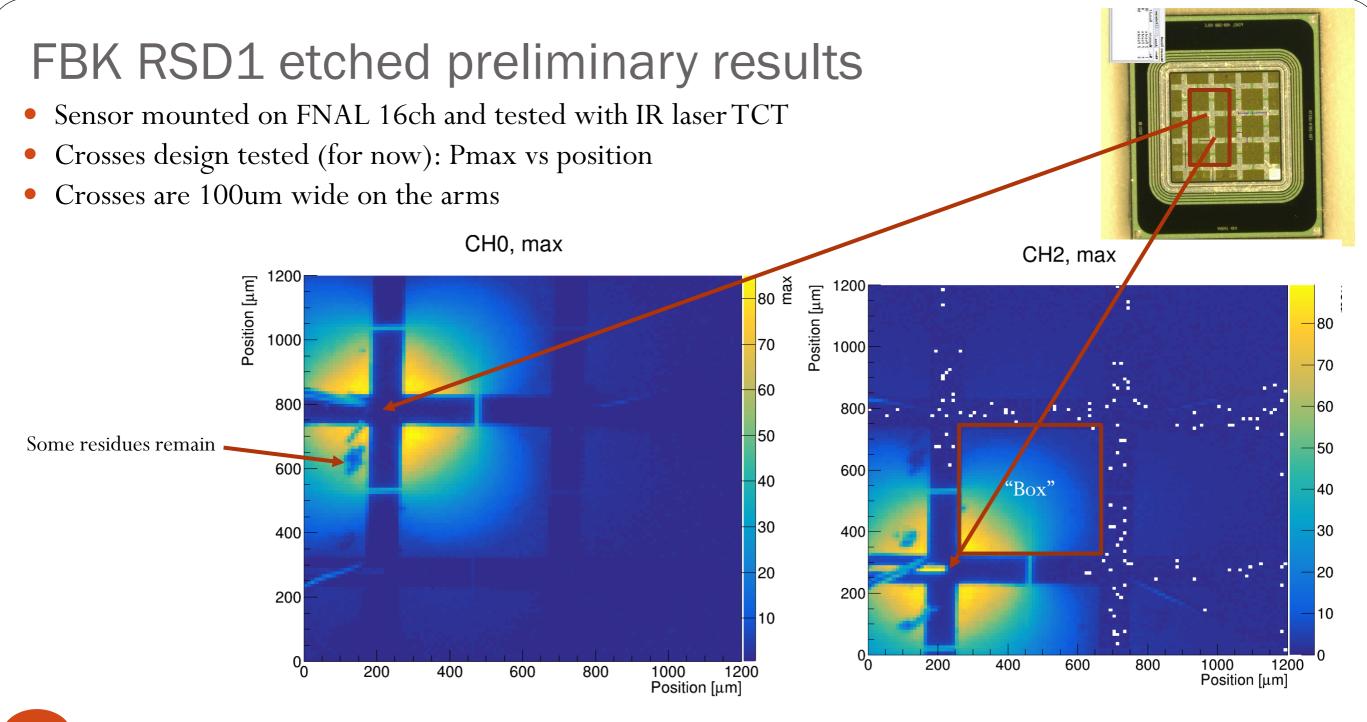
Rough polysilicon texture



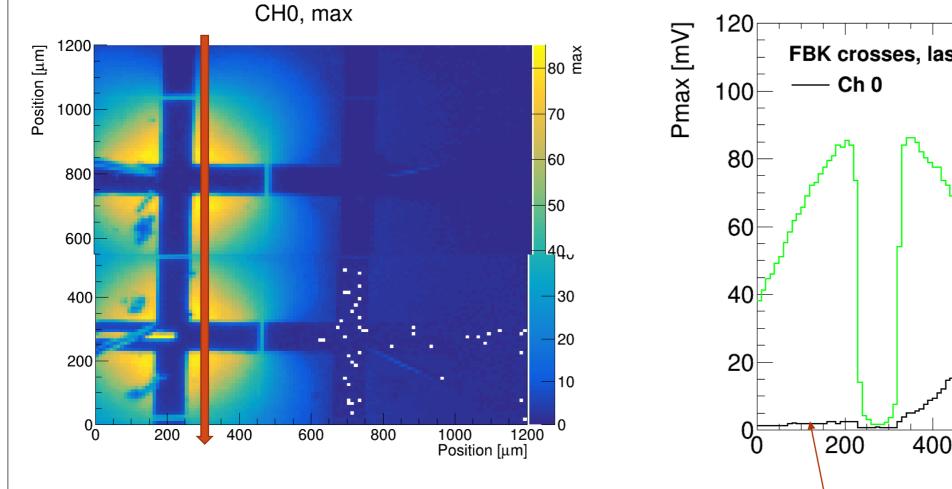
Damaged backside

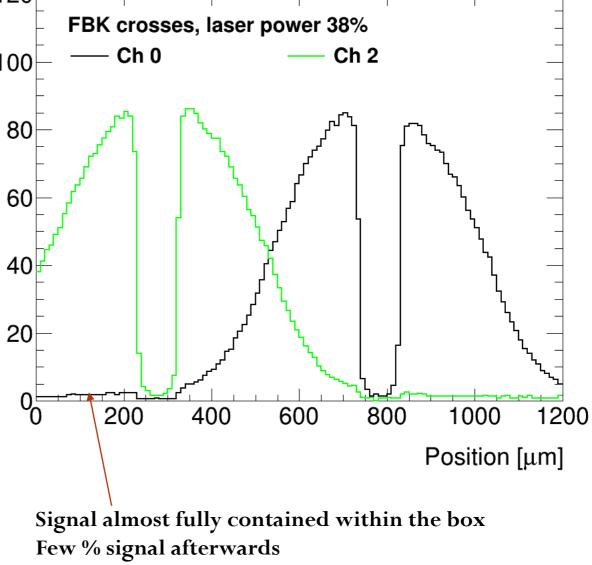




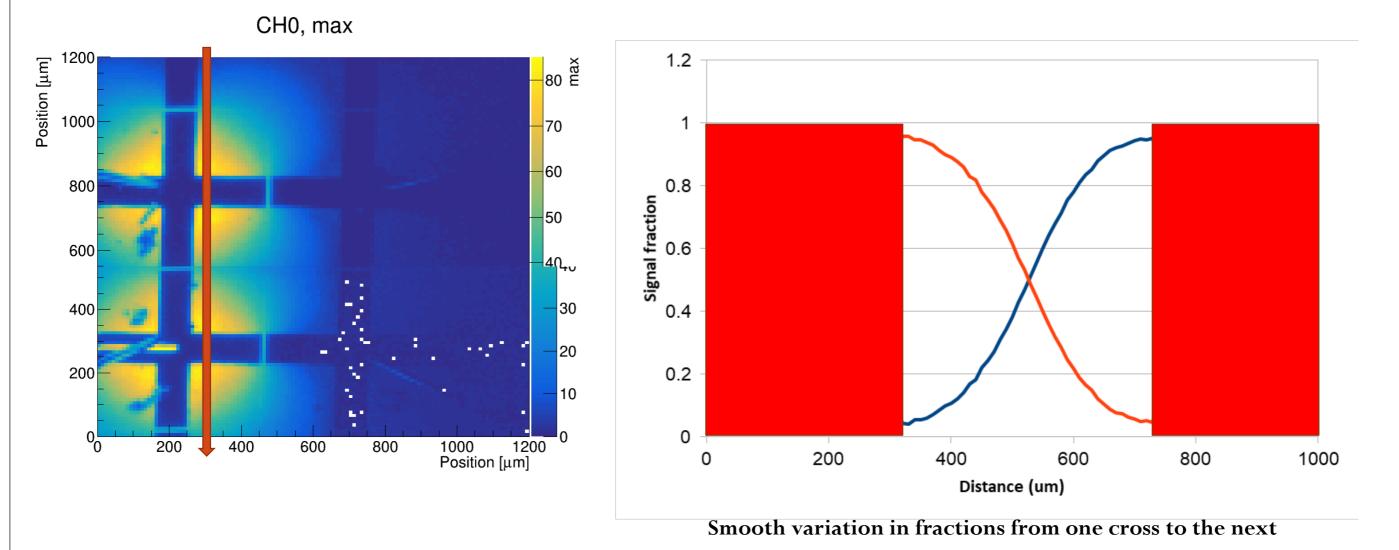


#### FBK RSD1 etched preliminary results (1D Pmax profile)



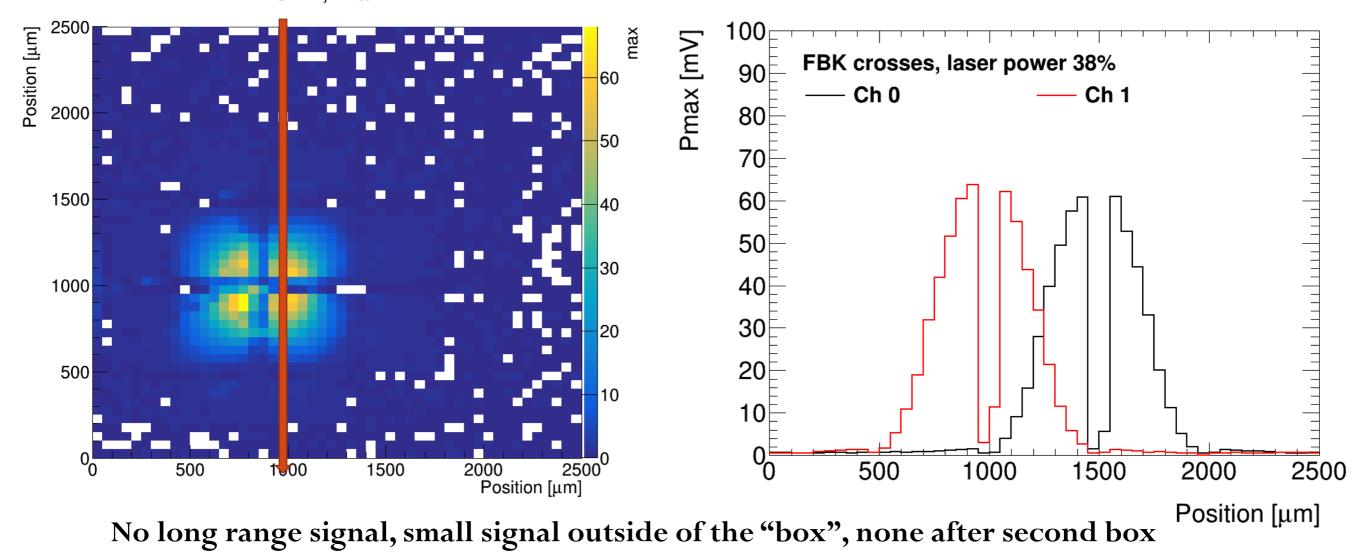


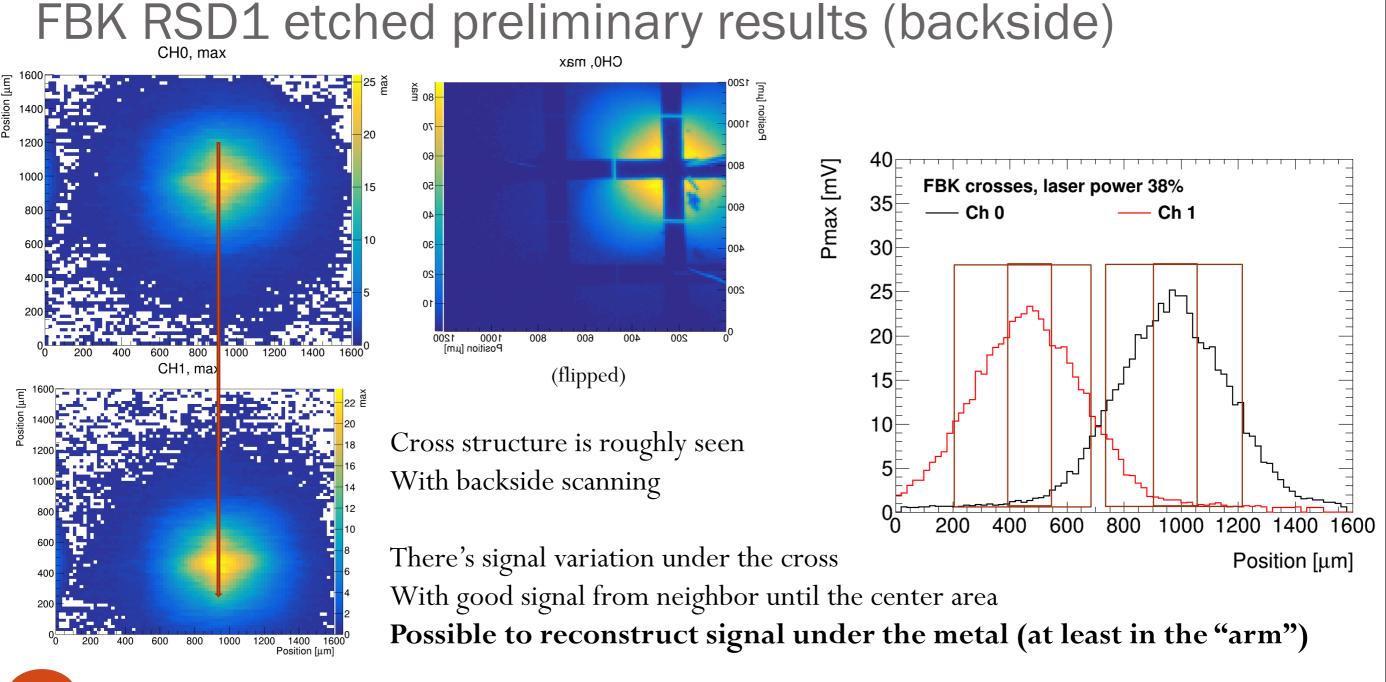
#### FBK RSD1 etched preliminary results (fractions)



#### FBK RSD1 etched preliminary results (entire sensor)

CH1, max

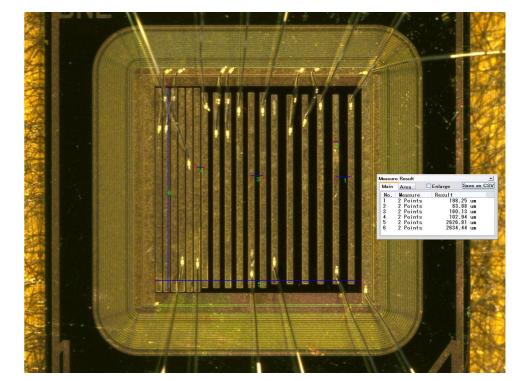


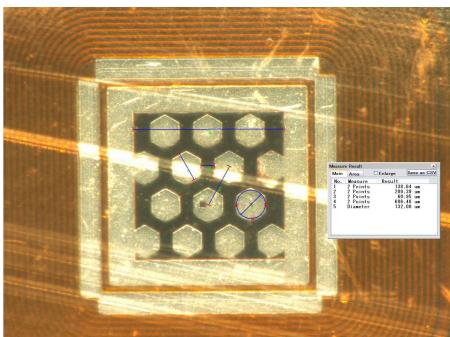


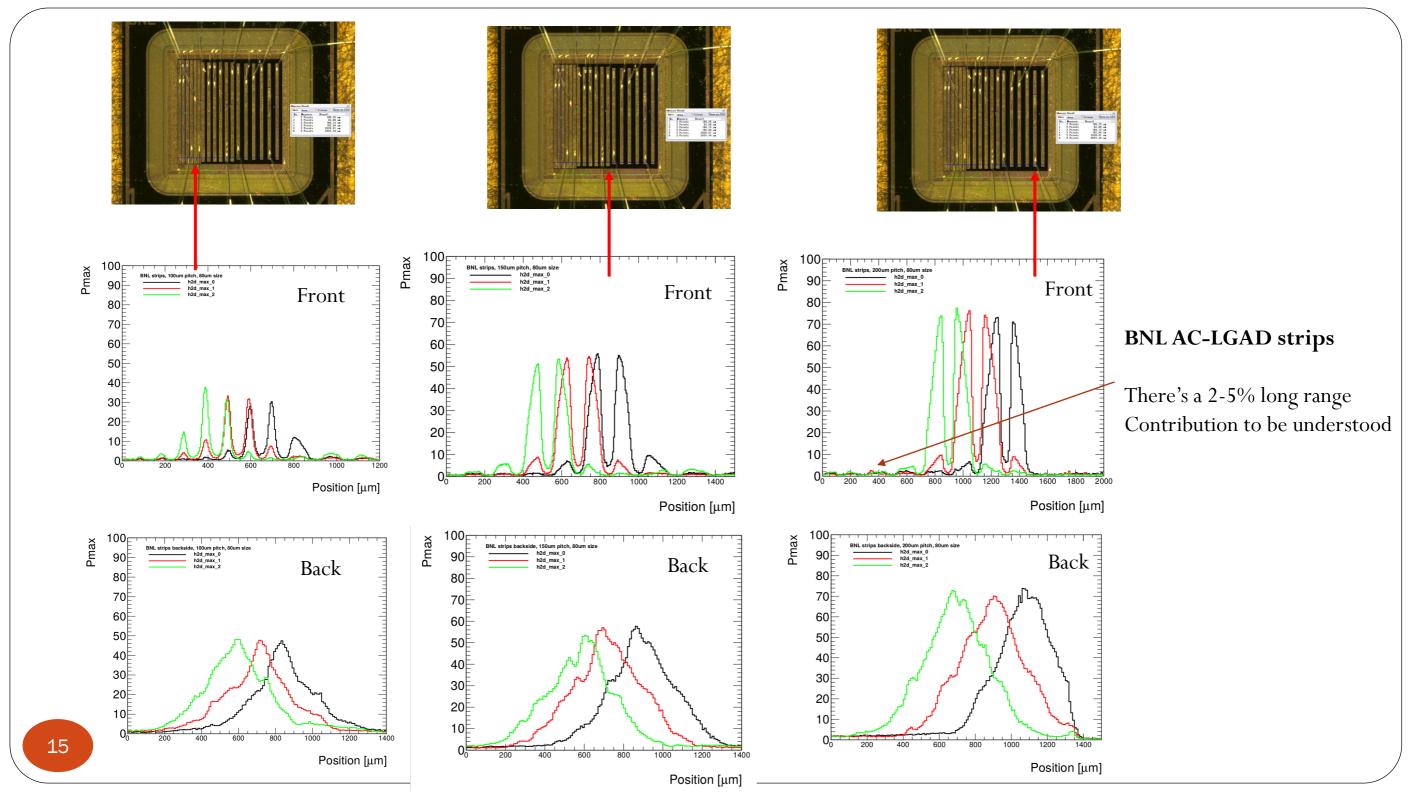
#### **BNL AC-LGAD testing**

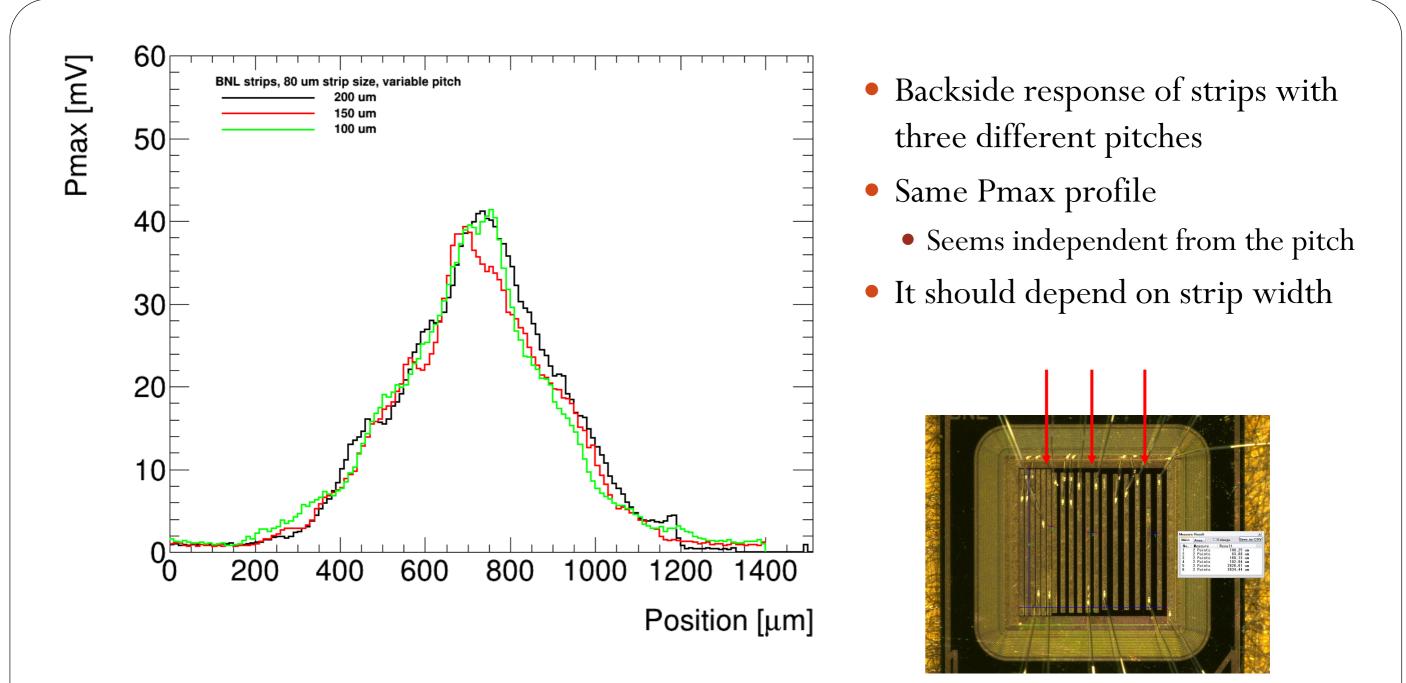
#### **BNL AC-LGAD** geometries

- BNL AC-LGADs laser studies at UCSC
- Sensors under study: strips and hexagons
- Strips with different pitches:
  - 80um strip width
  - 200um, 150um, 100um pitch
- Hexagons:
  - 200um pitch
  - 130um hexagon diameter
- Sensors etched on the backside at BNL to allow backside illumination





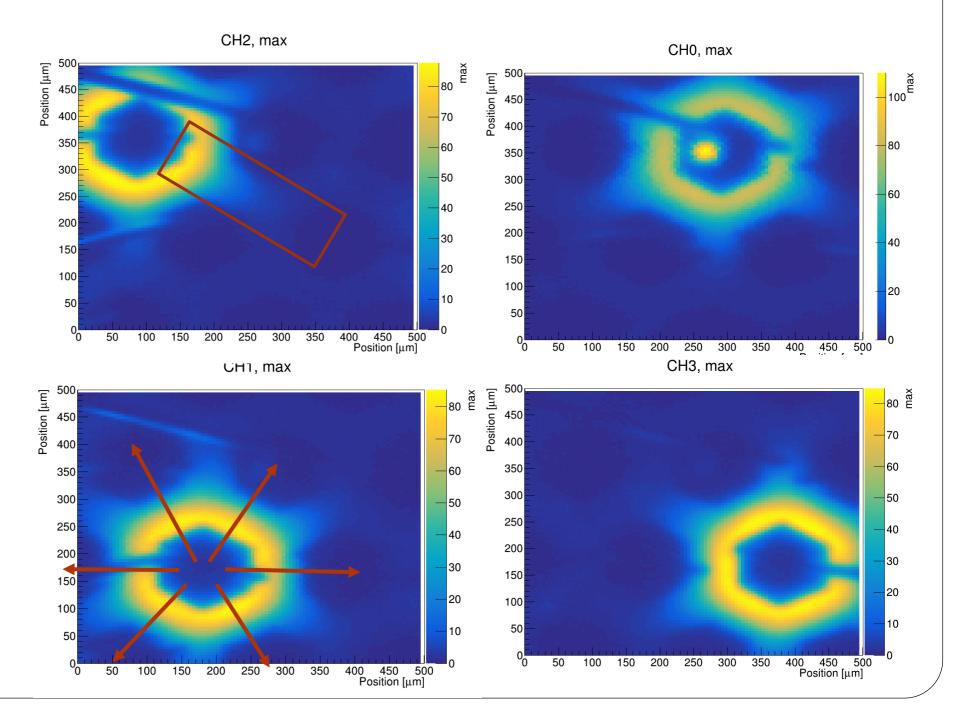




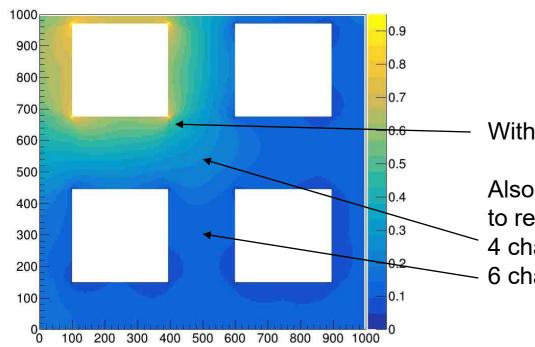
#### For master formula method see: https://arxiv.org/abs/2007.09528

#### **BNL Hexagons**

- Read out 4 hexagons
- Use master formula for position reconstruction
- Elementary "box" that needs 4ch for reconstruction in between
  - Ideally reconstruction also work under the metal using all 6 neighbors
- Hexagons are approximated to circles in master formula



# Master formula fraction calculation



CH2

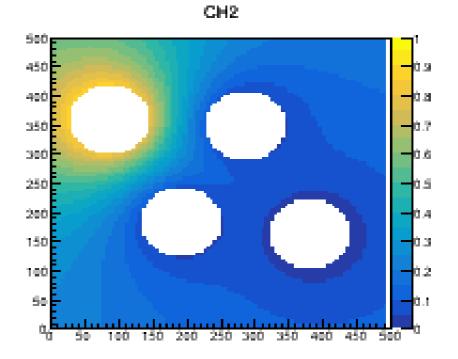
With square pads there are troublesome spots in the master formula

Also different "regions" in between pads that require a different number of pads to reconstruct e.g. 4 channels

- 6 channels

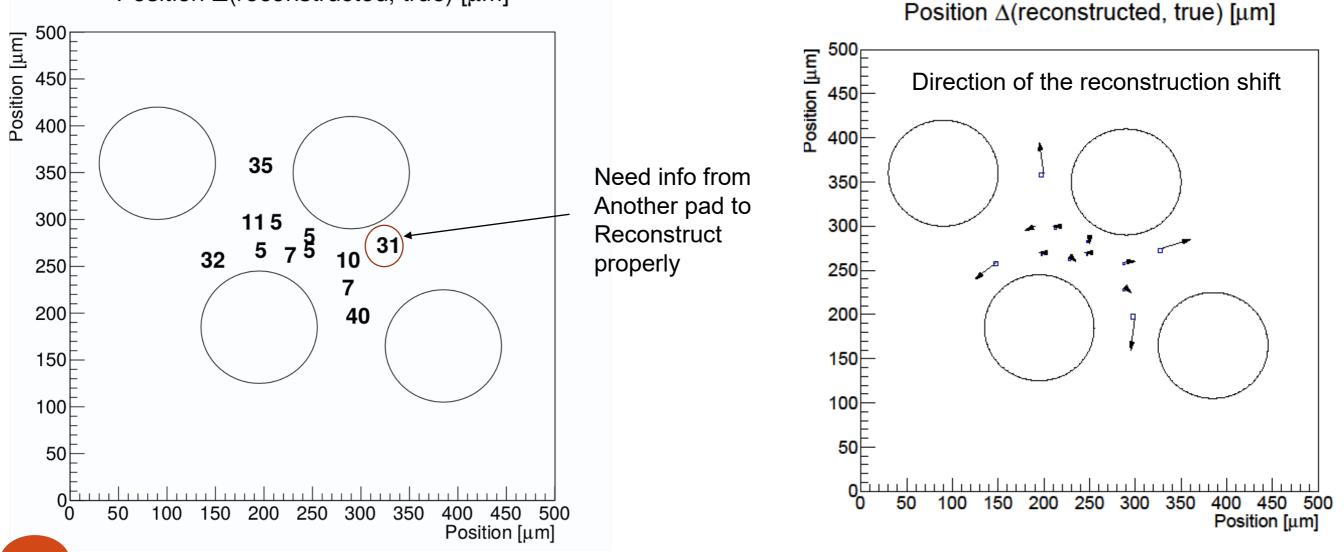
Hexagons are approximated with circles with circles the master formula is very smooth With staggered configuration the reconstruction should be more homogeneous

Note: master formula is not the most efficient algorithm, see Slides from Filippo on ML reconstruction next!



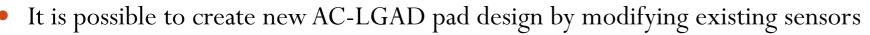
# Position (reco-true) is <10um in central region (not resolution)

Position  $\Delta$ (reconstructed, true) [ $\mu$ m]

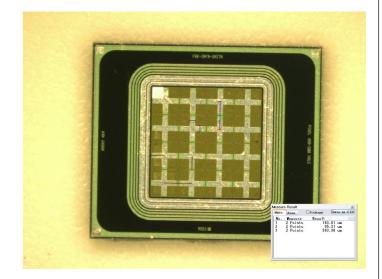


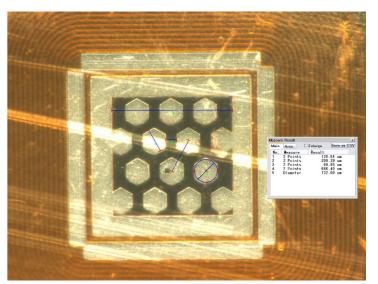
#### Conclusions





- Procedure is time consuming but if foreseen at production level might be faster
- Idea: produce fully metalized general purpose sensors to be etched for the prototype application
- Results from crosses design are very promising
  - Signal is mostly contained in "boxes" and reconstruction is streamlined
  - Reconstruction under cross is possible
  - Improving the design: cross with 100x100 bonding pad in the middle and very thin arms
- Other geometries to be tested soon
- AC-LGAD strips
  - Pmax profile does not seem to be dependent on the strip pitch
  - Long range effect to be understood (cross-talk with neighbors or N+?)
- AC-LGAD hexagons
  - Improved design to have better reconstruction outside and inside metal using all neighbors





#### Many thanks to the SCIPP group students and technicians!

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# Backup